

Notice of References Cited

Application/Control No.

10/535,388

Applicant(s)/Patent Under
Reexamination
KUSUNOKI ET AL.

Examiner

Aaron Williams

Art Unit

4135

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2002/0027411	03-2002	Bae et al.	313/461
	B	US-			
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	I	US-			
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	K	US-			
	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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